

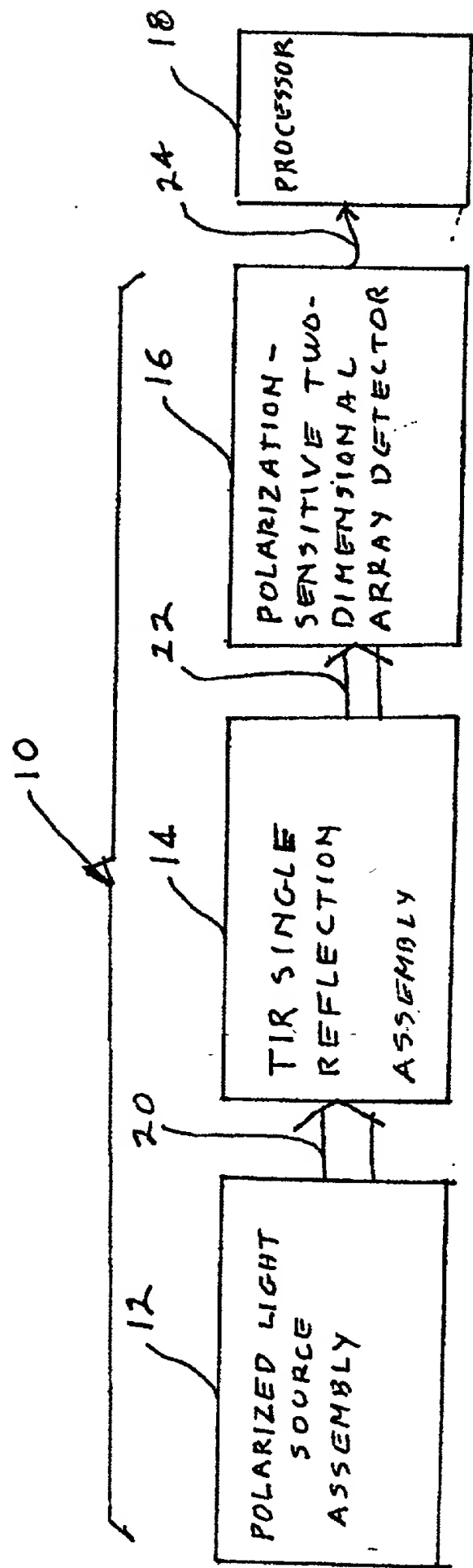
[illegible]

Fig 1

FIG. 2 is a schematic diagram of a system 10 for measuring the thickness of a film 14 on a substrate 16. The system 10 includes a light source 26, a collimating lens 28, a beam splitter 30, a focusing lens 32, a sample stage 34, a detector 36, and a control unit 38. The light source 26 emits a beam of light 24 that passes through the collimating lens 28 and is reflected by the beam splitter 30. The light 24 then passes through the focusing lens 32 and is focused onto the sample stage 34. The sample stage 34 is positioned above the film 14 on the substrate 16. The light 24 is reflected by the film 14 and passes through the detector 36. The detector 36 is connected to the control unit 38, which is used to measure the thickness of the film 14.

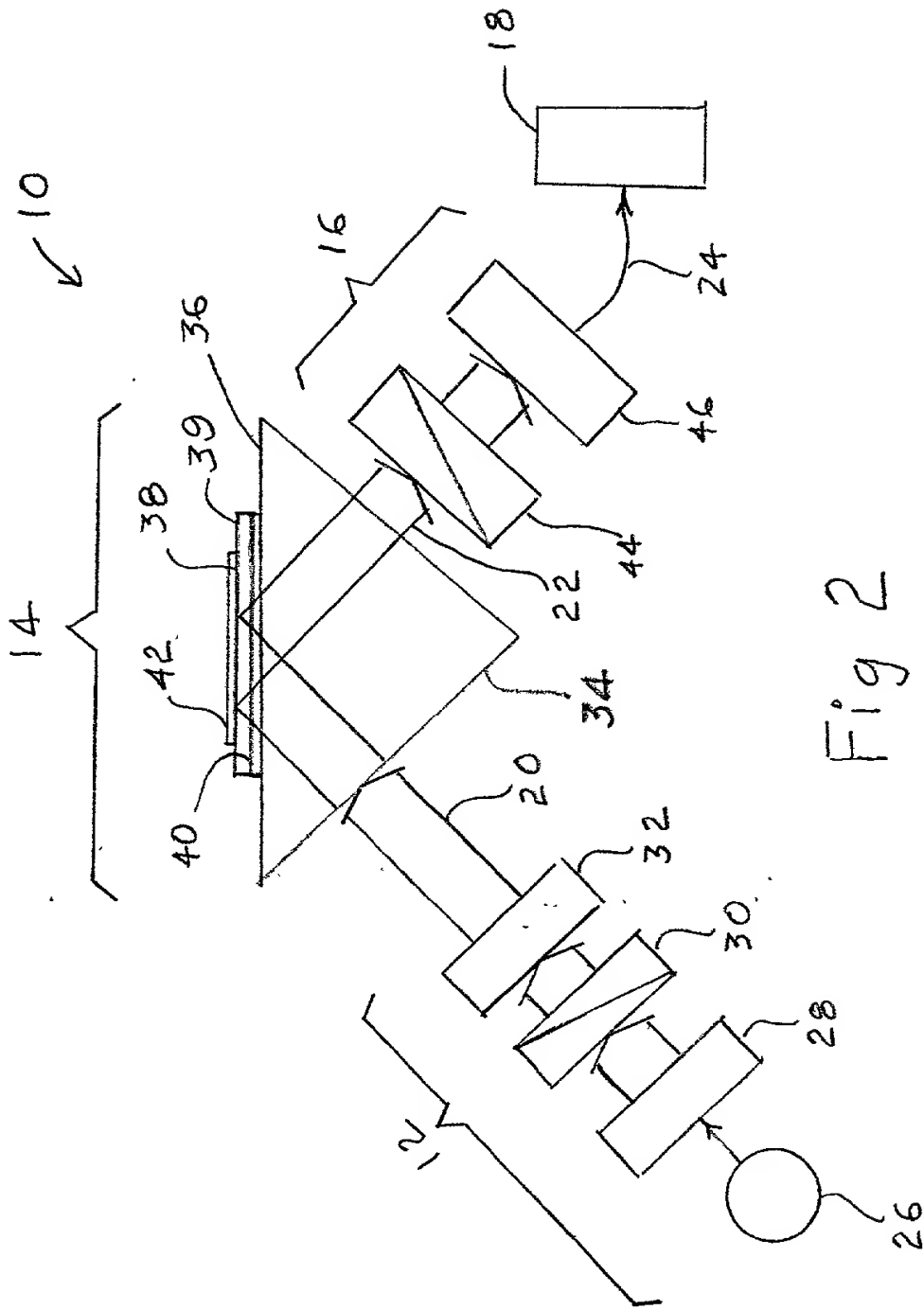


Fig 2

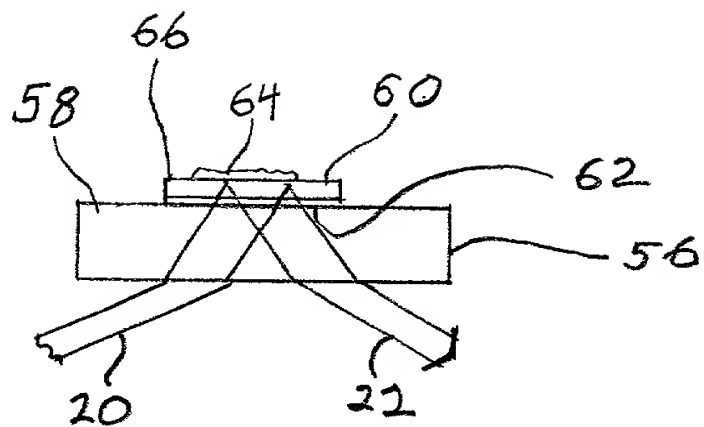


Fig 4

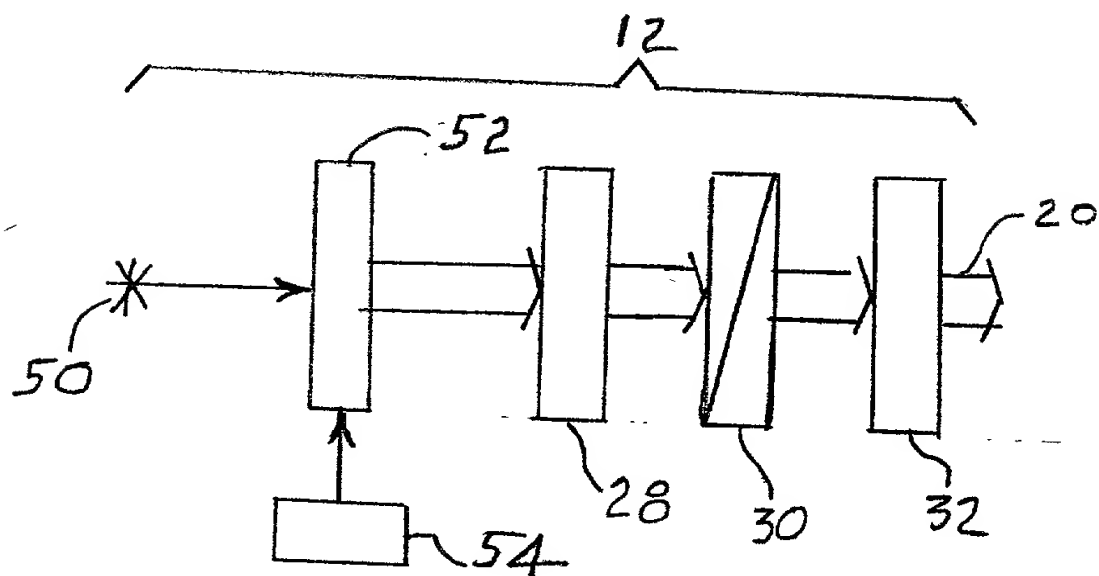


Fig 3

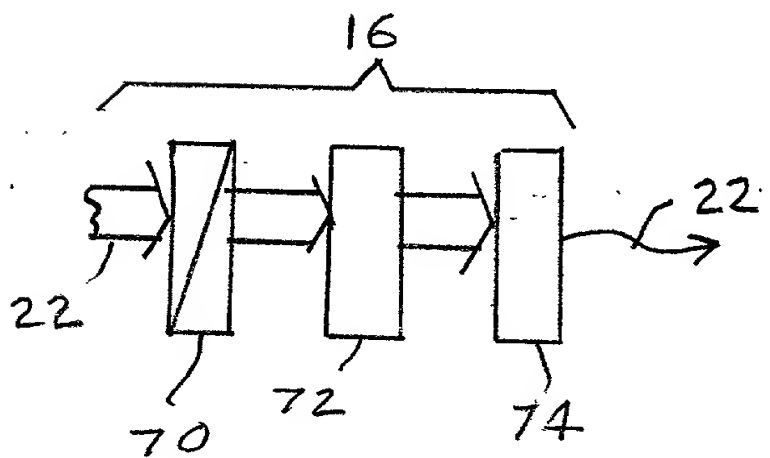


Fig 5

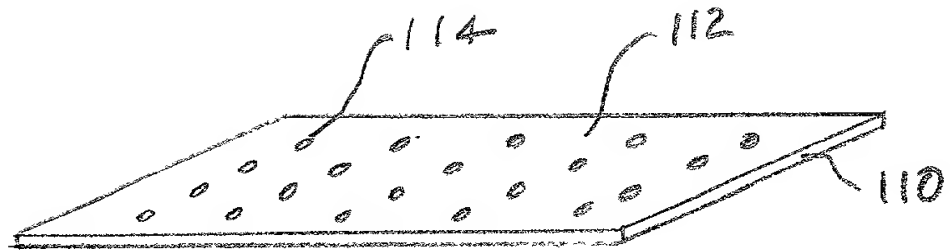


Fig 6

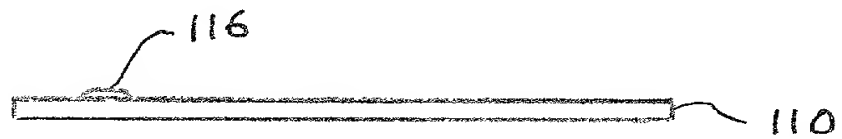


Fig 7

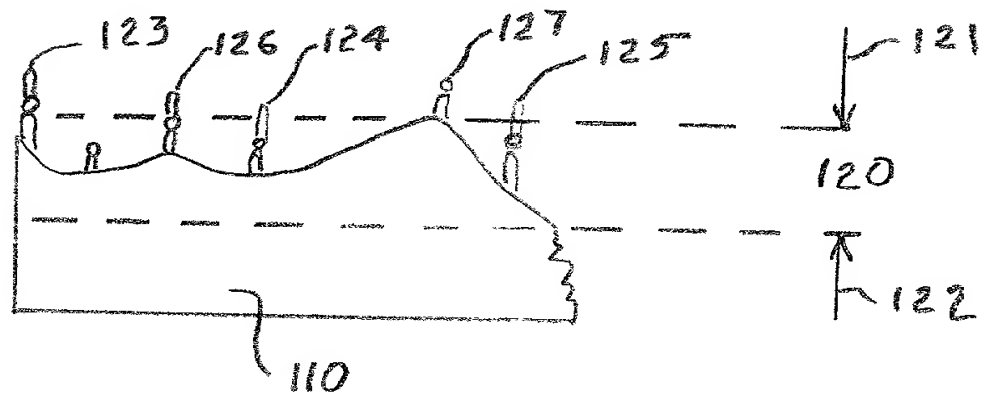


Fig 8 (PRIOR ART)

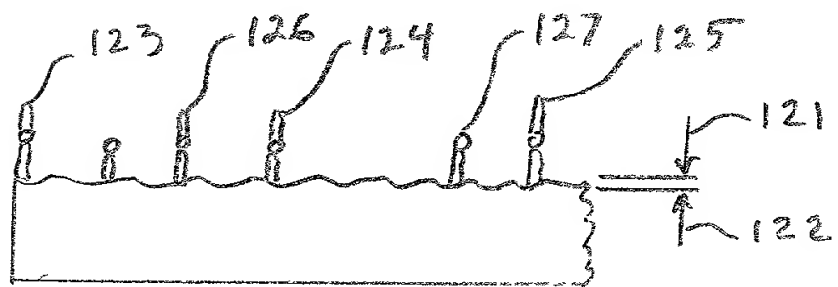


Fig 9

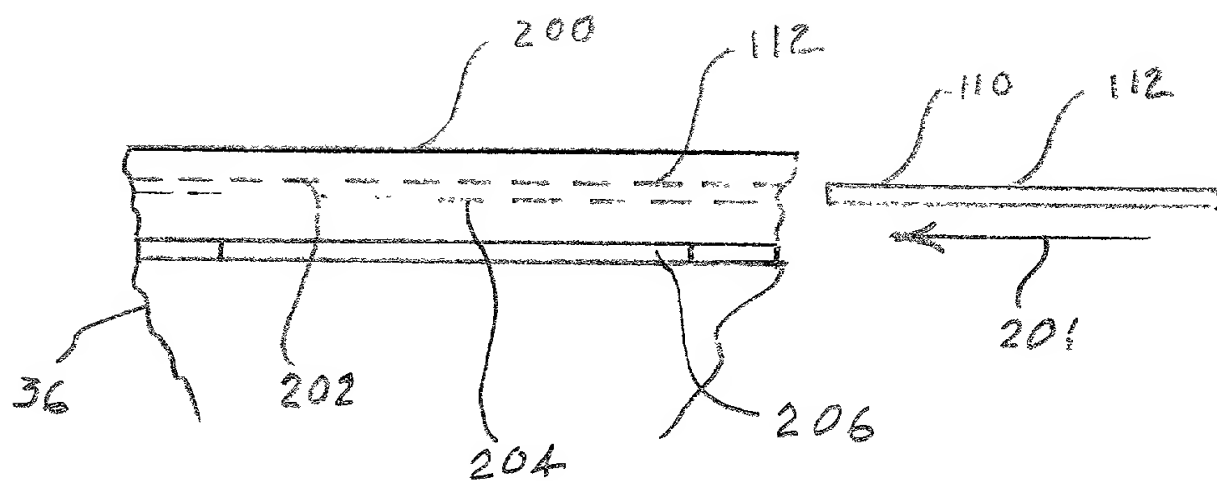


Fig 10

